



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

APPLICATION NO.: 09/757,583

CONFIRMATION NO. 8388

FIRST NAMED INVENTOR: Matsudo

FILING DATE: 01/11/2001

ART UNIT: 2823

EXAMINER: Nguyen, Khem

DOCKET NO.: 033082.065

FOR: METHOD FOR DEPOSITING TUNGSTEN SILICIDE FILM AND METHOD  
FOR PREPARING GATE ELECTRODE/WIRING

**AMENDMENT AND RESPONSE TO FINAL OFFICE ACTION**

BOX AF  
Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

A response to the Office Action mailed March 31, 2004 is being timely filed.

**AMENDMENT TO THE CLAIMS** section begins on page 2.

**REMARKS** begin on page 8 of this paper.

Please Enter,  
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07/14/04